



<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	<b>Attorney Docket No:</b> LAMIP106.A	<b>U.S. Serial No:</b> 09/785,999
	<b>Applicant:</b> Jay E. Uglow et al.	
	<b>Filing Date:</b> February 16, 2001	<b>Group:</b> 2813

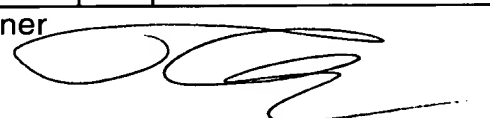
### U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
TSP	A	6,054,379	04/2000	YAU et al.			
TSP	B	6,211,063	04/2001	LIU et al.			
	C						
	D						
	E						
	F						
	G						
	H						
	I						
	J						
	K						

### Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
	L							
	M							
	N							
	O							
	P							

### Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
TSP	R	WOLF et al., "Silicon Processing for the VLSI Era Volume 1: Process Technology," Lattice Press, 1986, <del>(3 pages)</del> pp 194
	S	
	T	
Examiner 		Date Considered 12/28/02

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.